

Abstract of Disclosure

The invention relates to a device for loading substrates into and unloading them from a clean room, comprising a lock device onto which a transport box for receiving the substrates can be placed and which is fitted with a hermetically sealing lock opening, and a process unit adjacent to the lock opening. To allow for a valid adjustment of the lock device in relation to the process unit even when the lock device is exchanged, the invention provides for an adapter device to be positioned between the process unit and the lock device to which the lock device can be removably fixed and which is maintained at the level of the process unit and can be adjustably aligned in relation to same.

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